LISTING OF THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

- 1. (Currently Amended) In a superjunction semiconductor device; a semiconductor body region of a first conductivity type and having parallel top and bottom surfaces; a plurality of spaced pylons of the other conductivity type extending through at least a portion of the thickness of said body region; a body; a plurality of MOSgated structures, each respective MOSgated structure including a source region disposed in a channel body region which is positioned above and in contact with each one of said pylons, each of said pylons having a substantially constant diameter, the major length of said pylons extending from their ends which are closest to said bottom surface being in charge balance with the body region surrounding them; the remaining length of each of said pylons at the top thereof having a higher concentration than that of said major length whereby avalanche current is at least partly directed toward the center of the top of said pylon and away from the R_{br} region in said channel and a region beneath said source region.
- 2. (Original) The device of claim 1 wherein said charge in said remaining length is up to about 20% greater than that in said major length of said pylon.
- 3. (Original) The device of claim 1 wherein said remaining length of said pylons is less than about 25% of the length of said pylon.
- 4. (Original) The device of claim 2 wherein said remaining length of said pylons is less than about 25% of the length of said pylon.
- 5. (Currently Amended) A P type semiconductor pylon in an N type body for a superjunction device; said P type pylon having an increased concentration at its top end which is greater than and overbalances the concentration of the surrounding N type body; the remainder of the length of said pylon being in charge balance with the surrounding N type body, said pylon having a substantially constant diameter.

- 6. (Original) The device of claim 5 wherein said charge in said remaining length is up to about 20% greater than that in said major length.
- 7. (Original) The device of claim 5 wherein said remaining length of said pylons is less than about 25% of the length of said pylon.
- 8. (Original) The device of claim 6 wherein said remaining length of said pylons is less than about 25% of the length of said pylon.
- 9. (Currently Amended) A superjunction device having improved avalanche capability; said device comprising a semiconductor wafer body of one conductivity type and having a major electrode on the bottom of said wafer; a plurality of identical and spaced pylons of the other conductivity type extending through at least a portion of the thickness of said wafer; at least the lower portions of said pylons being in charge balance with said wafer body; and a portion of the top of said pylons having a greater charge than that of said lower portions, each of said pylons having a substantially constant diameter.
- 10. (Original) The device of claim 9 wherein the charge in said top of said pylons is about at least 15 to 20% greater than that of said lower portions.
- 11. (Original) The device of claim 9 wherein the length of said portion of said top is less than about 25% of the full length of said pylons.
- 12. (Original) The device of claim 10 wherein the length of said portion of said top is less than about 25% of the full length of said pylons.
- 13. (Currently Amended) The device of claim 9 which further includes <u>a</u> MOSgated structures <u>structure</u> disposed at the top of each of said pylons; <u>said each MOSgated structure</u> comprising a <u>channel body</u> region of said opposite conductivity type and which extends across

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and overlaps its respective pylon; [[a]] respective source $\frac{\text{regions}}{\text{regions}}$ of said one conductivity extending into $\frac{\text{each of each channel regions}}{\text{said body region}}$ and defining [[R_b]] regions in said $\frac{\text{channels body region}}{\text{sources periphery of said pylon top}}$; a gate structure extending across respective invertible channel regions between said $\frac{\text{respective}}{\text{source regions}}$ and $\frac{\text{channel regions}}{\text{said wafer body}}$ at the top of said wafer $\frac{\text{body}}{\text{said pylon}}$; and a source electrode extending over the top of said wafer $\frac{\text{body}}{\text{said pylon}}$ and in contact with $\frac{\text{each of}}{\text{said respective}}$ source $\frac{\text{regions}}{\text{regions}}$ and $\frac{\text{channel regions}}{\text{said body region}}$.

- 14. (Original) The device of claim 13 wherein the charge in said top of said pylons is about at least 15 to 20% greater than that of said lower portions.
- 15. (Original) The device of claim 13 wherein the length of said portion of said top is less than about 25% of the full length of said pylons.
- 16. (Original) The device of claim 14 wherein the length of said portion of said top is less than about 25% of the full length of said pylons.

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